CLAIM AMENDMENTS

1.-21. (Canceled)

- 22. (Currently Amended) A semiconductor base comprising a substrate and a semiconductor GaN crystal formed on said substrate by vapor phase growth, wherein
- (a) the semiconductor crystal is a GaN group semiconductor crystal defined by $Al_x Ga_{1-x-y} In_y N$, where $0 \le x \le 1$ and $0 \le y \le 1$,
- (b) the substrate is a base on which is the grown-semiconductor <u>GaN</u> crystal, and which is made of sapphire, wherein the sapphire is C-plane, A-plane, or R-plane, SiC, wherein the SiC is 6H, 4H, or 3C, GaN, Si, Spinel, ZnO, GaAs, or NGO,
 - (e) (b) the substrate has a concavo-convex surface as a crystal growth plane, and
- (d) (c) the semiconductor <u>GaN</u> crystal having been grown laterally from the <u>an</u> upper part of the convex part of the concavo-convex surface and having been grown from a surface of the concave part as starting points, such that the crystal grown laterally from the upper part of the convex part of the concavo-convex surface and the crystal grown from the surface of the concave part are joined to cover the concavo-convex surface of the substrate.
- 23. (Currently Amended) The semiconductor base of claim 22, wherein the concave part of the substrate is filled with a semiconductor <u>GaN</u> crystal and devoid of a eavity.
- 24. (Previously Presented) The semiconductor base of claim 22, wherein the convex parts of the crystal growth plane of the substrate form parallel stripes.
- 25. (Currently Amended) The semiconductor base of claim 24, wherein the longitudinal direction of the stripe is stripes are the <1-100> direction of the GaN group semiconductor crystal.
- 26. (Currently Amended) The semiconductor base of any of claims 22-25, wherein the GaN crystal is used as the first semiconductor crystal, wherein the surface of the first semiconductor crystal of the semiconductor base has a second concavo-convex surface, wherein and comprises a second semiconductor crystal having been grown laterally from the an upper part of the convex part of the second concavo-convex surface and having been grown from a surface of the concave part as starting points, such that the crystal grown laterally from the upper part of the convex part of the concavo-convex surface and the crystal

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grown from the surface of the concave part are joined to cover the <u>second</u> concavo-convex surface, and wherein the second semiconductor crystal is a GaN group semiconductor crystal <u>defined by $Al_x Ga_{1-x-y} In_y N$, where $0 \le x \le 1$ and $0 \le y \le 1$.</u>

- 27. (Currently Amended) The semiconductor base of claim 26, wherein the concave part of said substrate is filled with a semiconductor <u>GaN</u> crystal and devoid of a cavity.
- 28. (Currently Amended) A semiconductor base comprising plural semiconductor crystal layers formed in multiplicity by making a surface of the second semiconductor crystal layer of the semiconductor base of claim 26 a <u>third</u> concavo-convex surface, and similarly growing thereon[[,]] a third semiconductor crystal layer by vapor phase growth or by repeating a similar step.
- 29. (Currently Amended) A semiconductor base comprising plural semiconductor crystal layers formed in multiplicity by making a surface of the second semiconductor crystal layer of the semiconductor base of claim 27 a third concavo-convex surface, and similarly growing thereon[[,]] a third semiconductor crystal layer by vapor phase growth or by repeating a similar step.
- 30. (New) The semiconductor base of claim 22, wherein the area of the concavoconvex surface of the substrate occupied by the convex part is not more than 50%.
- 31. (New) The semiconductor base of claim 22, wherein the convex part of the concavo-convex surface of the substrate is an island type intersperse convex part, a stripe type convex part consisting of convex lines, a lattice convex part, or any of the foregoing convex parts which is formed by a curve.
- 32. (New) The semiconductor base of claim 24, wherein the longitudinal direction of the stripes are the <11-20> direction of the GaN crystal.
- 33. (New) The semiconductor base of claim 24, wherein the convex part has a width of not more than 5 μ m.
- 34. (New) The semiconductor base of claim 22, wherein a buffer layer has been grown and then a GaN crystal has been grown on the concavo-convex surface of a substrate.

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35. (New) The semiconductor base of claim 34, wherein the buffer layer is a GaN low temperature buffer layer.